

<b>Notice of References Cited</b>	Application/Control No. 09/921,786	Applicant(s)/Patent Under Reexamination DREVILLON ET AL.	
	Examiner Carlos Ortiz-Rodriguez	Art Unit 2125	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-2002/0024668	02-2002	Stehle et al.	356/369
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kildemo et al., "Real time control of the growth of silicon alloy multilayers by multiwavelength ellipsometry"; Thin Solid Films, Dec. 1996; Vol. 290-291; pages 46-50.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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